

# 1997 Index

## IEEE Transactions on Plasma Science

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This index covers all technical items - papers, correspondence, reviews, etc. - that appeared in this periodical during 1997, and items from previous years that were commented upon or corrected in 1997.

The Author Index contains the primary entry for each item, listed under the first author's name, and cross-references from all coauthors. The Subject Index contains several entries for each item under appropriate subject headings, and subject cross-references.

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#### Vacuum breakdown; cf. Vacuum arcs

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#### Vacuum switches; cf. Vacuum circuit breakers; Vacuum interrupters

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### Y

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